Form PTO-1449 (Modified)	Atty Docket No.	Serial No.	
LIST OF PATENTS AND PUBLICATIONS	BARDP0124US	10/684,811	
FOR APPLICANT'S INFORMATION DISCLOSURE STATEMENT	Applicant: Kai Numssen et al.		
(Use several sheets if necessary)	Filing Date	Group	
3 Mag, Mil	October 14, 2003		

U.S. PATENT DOCUMENTS Date (MM/YYYY) Sub-Filing Date if Appropriate /BT/ 5,084,300 01/1992 Zander et al. 5,151,408 09/1992 Tanaka et al. 5,162,294 11/1992 Talvacchio et al. 5,712,227 01/1998 Higaki et al. 5,869,431 02/1999 Veal et al. 6,121,205 09/2000 Murakami et al. /BT/ 6,258,472 07/2001 Neumüller et al.

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		(MINDTTTT)				Yes	No
/BT/	197 50 598	11/1997	DE				
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	01063212	03/1989	JP				
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OTHER ART

Examiner Initial	Author, Title, Date, Pertinent Pages, etc.				
/BT/	Mukaida, Masashi et al. "In-Plane Orientation Control of C-Axis Oriented YBa ₂ Cu ₃ O ₇₋₈ Films on MgO Substrates by BaSnO ₃ Buffer Layers". <u>Japanese Journal of Applied Physics</u> . 38(1999):L926-L928.				
	Geerk, J. et al. "A 3-Chamber Deposition System for the Simultaneous Double-Sided Coating of 5-inch Wafers". <u>IEEE Transactions on Applied Superconductivity</u> . 11.1(2001):3856-3858.				
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/BT/	Zou, Zhigang et al. "Superconducting PrBA ₂ Cu ₃ O _x ". <u>Physical Review Letters</u> . 80.5(1998):1074-1077.				

EXAMINER	/Brian Talbot/	DATE CONSIDERED	04/24/2007
		<u> </u>	

EXAMINER:

Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.